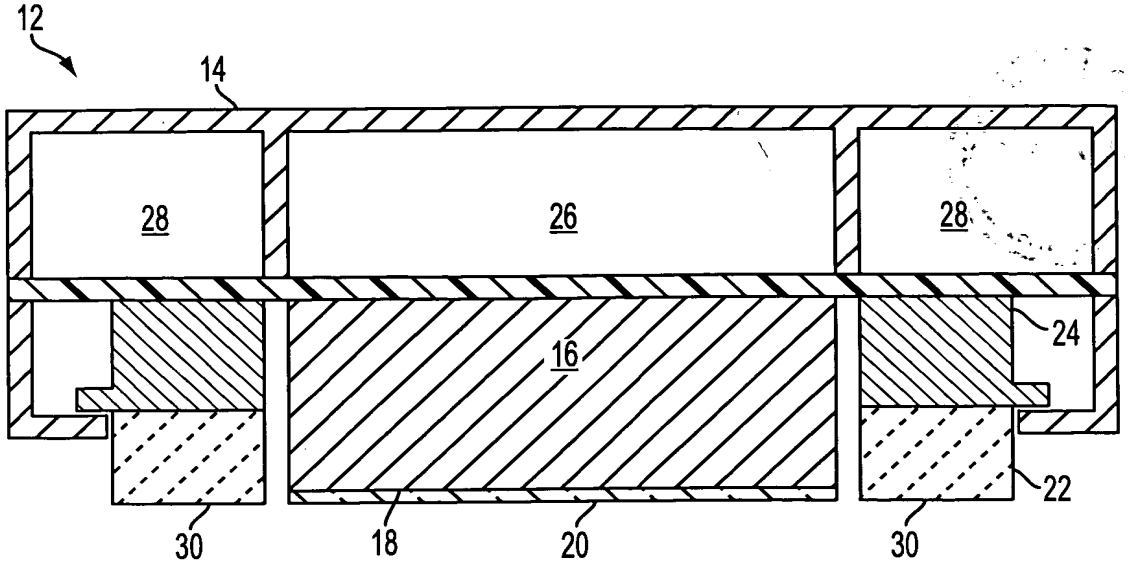

FIG. 1
(PRIOR ART)

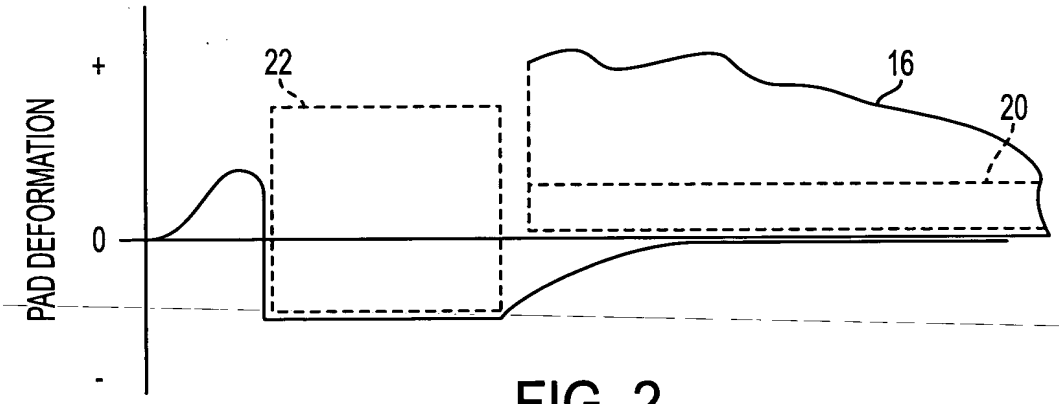

FIG. 2
(PRIOR ART)

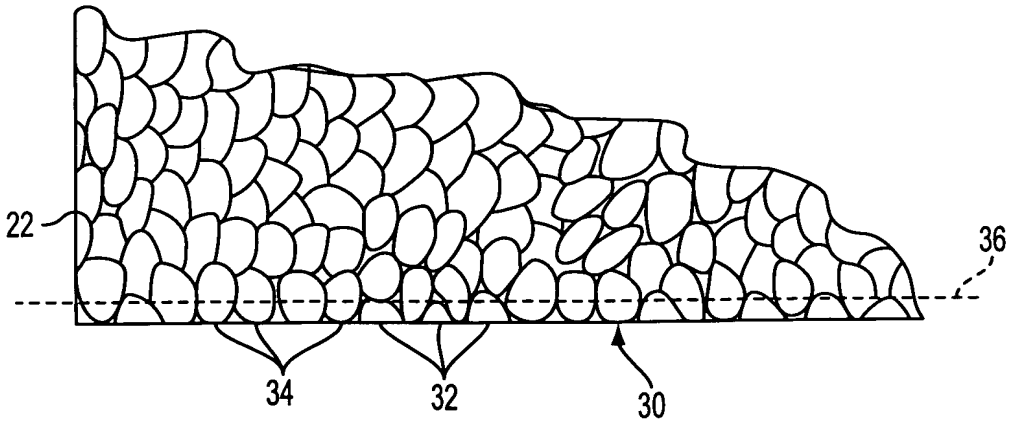

FIG. 3
(PRIOR ART)

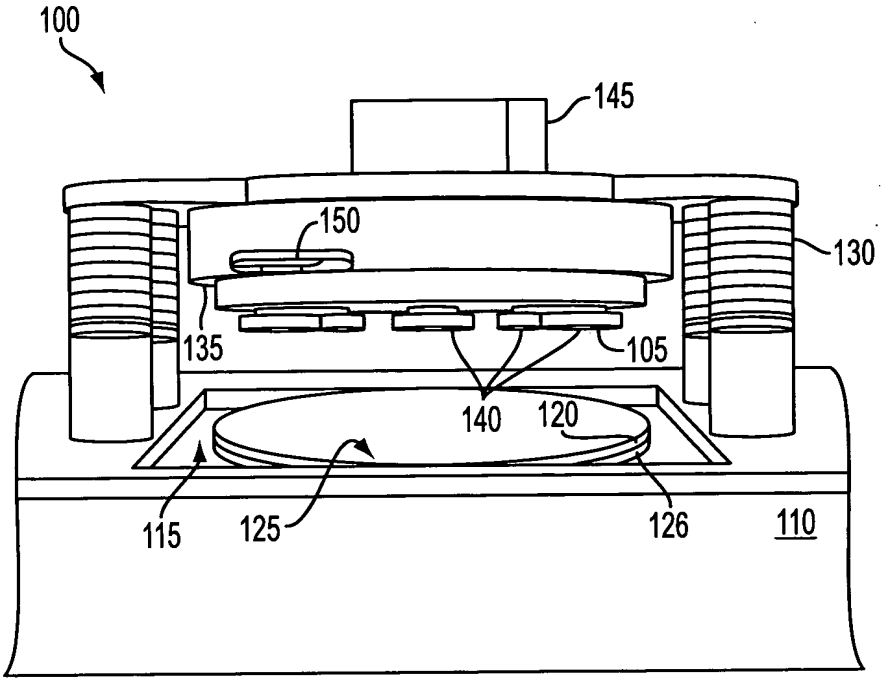

FIG. 4

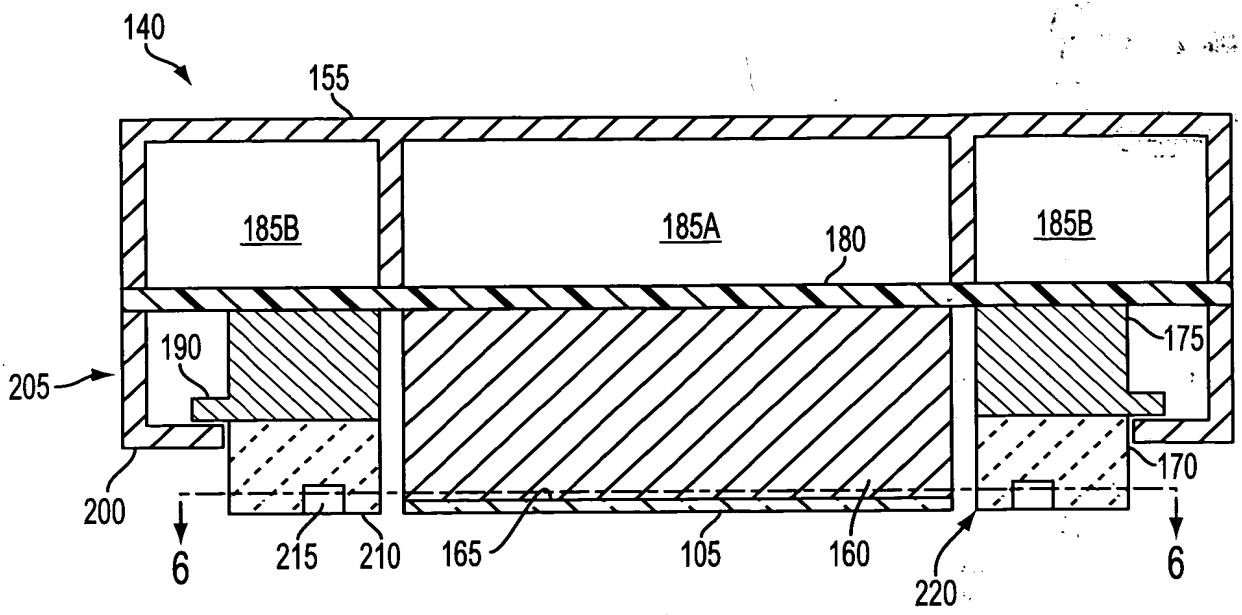
140
155
185B
185A
180
185B
190
205
175
200
170
6
215
210
165
105
160
220
6

FIG. 5

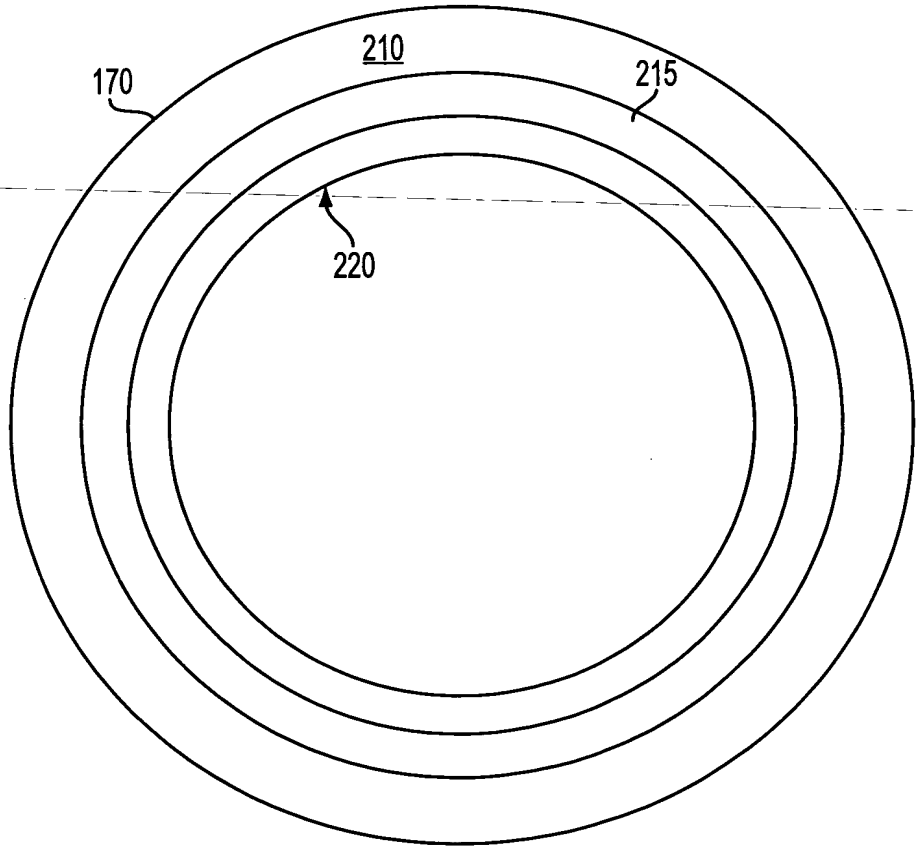
210
170
215
220

FIG. 6

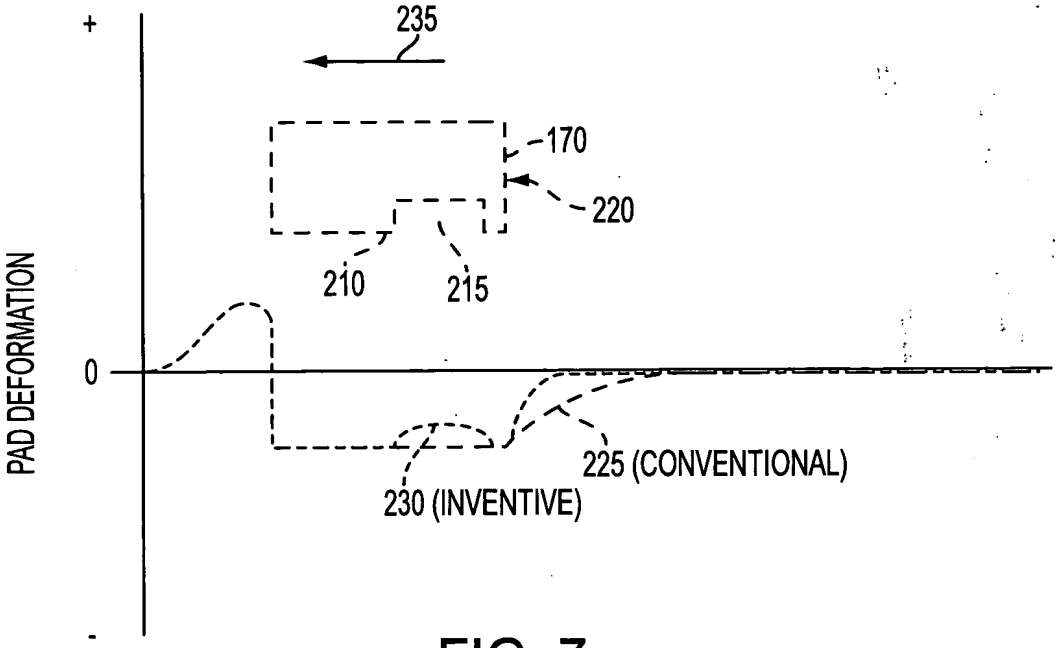

FIG. 7

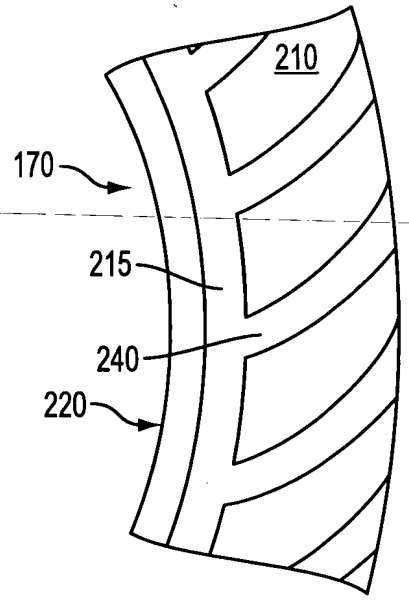

FIG. 8

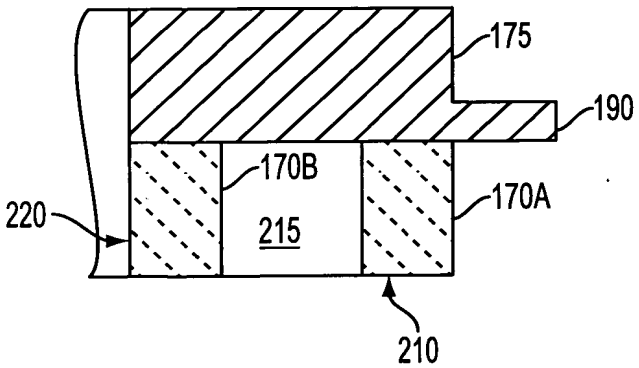

FIG. 9

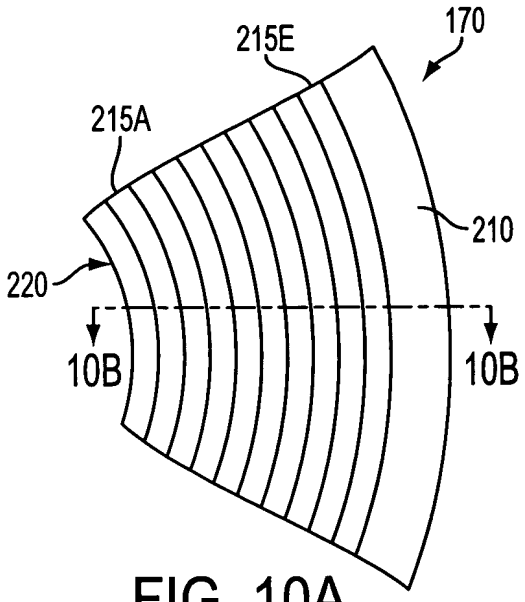

FIG. 10A

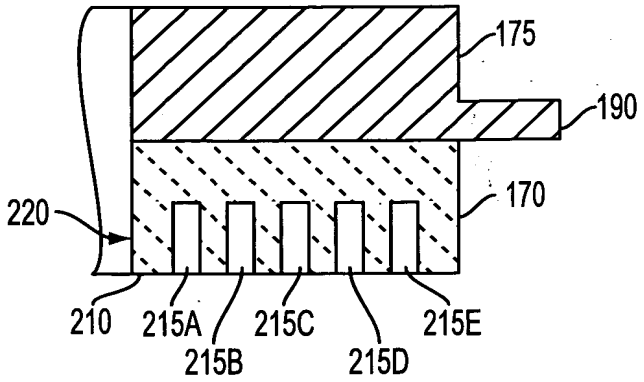

FIG. 10B

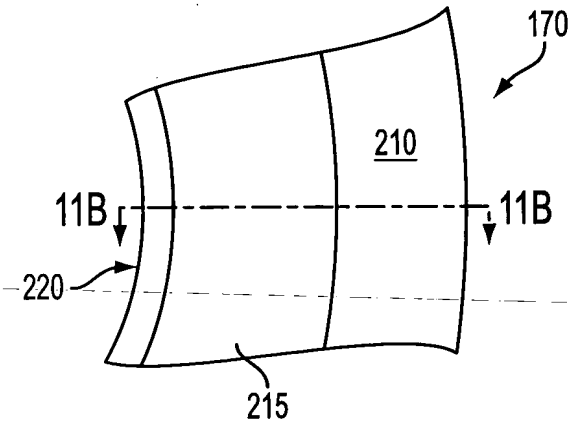

FIG. 11A

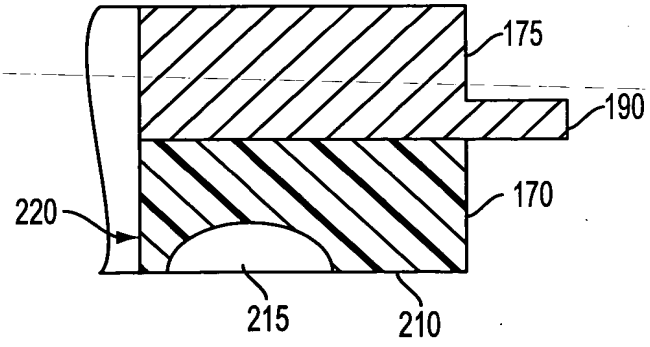

FIG. 11B

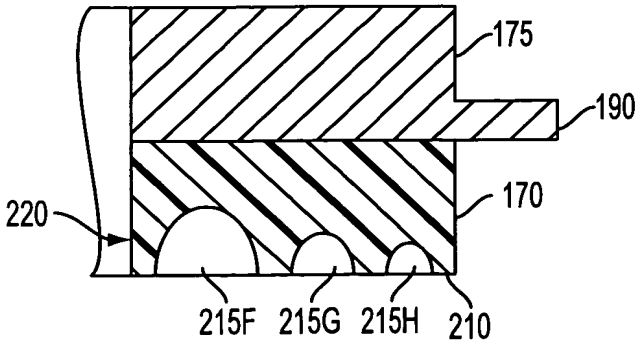

FIG. 12

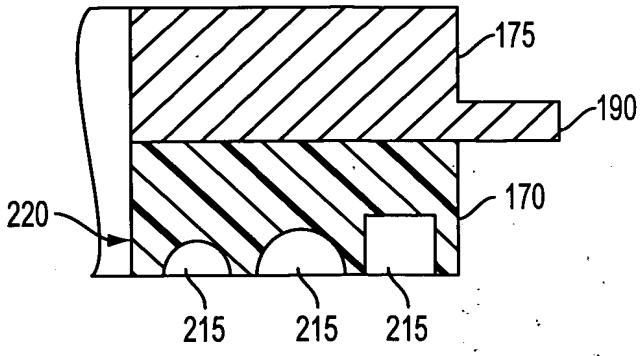

FIG. 13

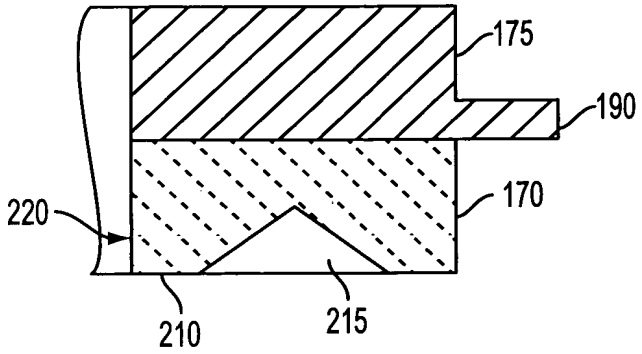

FIG. 14

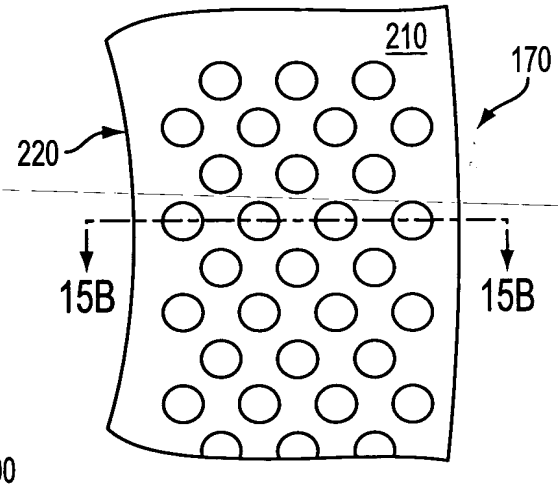

FIG. 15A

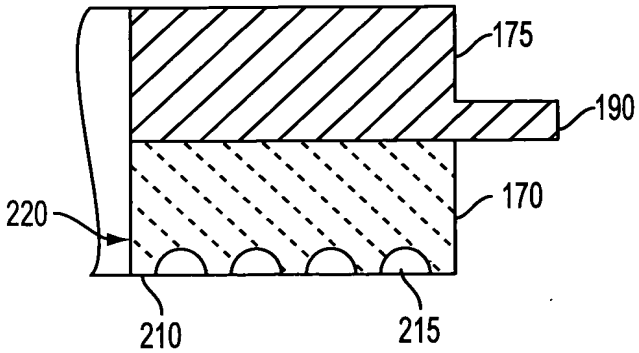

FIG. 15B

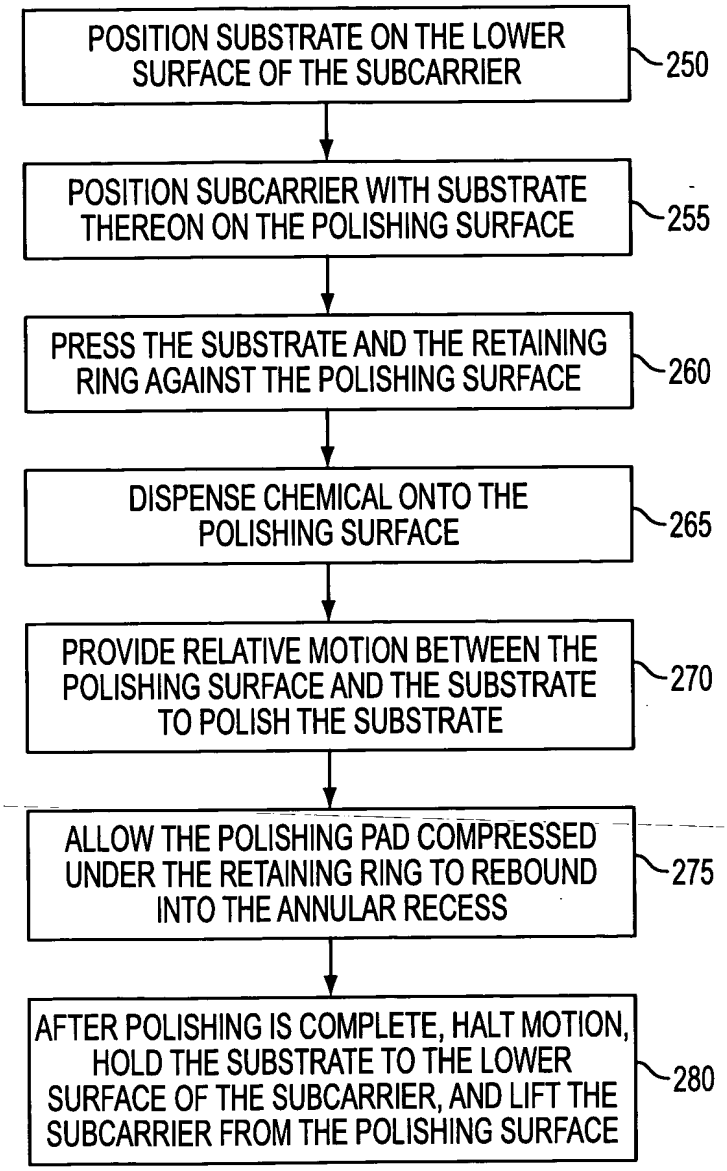
POSITION SUBSTRATE ON THE LOWER SURFACE OF THE SUBCARRIER
250
POSITION SUBCARRIER WITH SUBSTRATE THEREON ON THE POLISHING SURFACE
255
PRESS THE SUBSTRATE AND THE RETAINING RING AGAINST THE POLISHING SURFACE
260
DISPENSE CHEMICAL ONTO THE POLISHING SURFACE
265
PROVIDE RELATIVE MOTION BETWEEN THE POLISHING SURFACE AND THE SUBSTRATE TO POLISH THE SUBSTRATE
270
ALLOW THE POLISHING PAD COMPRESSED UNDER THE RETAINING RING TO REBOUND INTO THE ANNULAR RECESS
275
AFTER POLISHING IS COMPLETE, HALT MOTION, HOLD THE SUBSTRATE TO THE LOWER SURFACE OF THE SUBCARRIER, AND LIFT THE SUBCARRIER FROM THE POLISHING SURFACE
280

FIG. 16